

10/706624

Examiner: PASCHALL, MARK

GAU: 3742

Classification: 219/121.430


Inventor: SHIMIZU, AKIRA, et al

Status: 30 - DOCKETED NEW CASE - READY FOR EXAMINATION

Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Bib Data report

Application Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Application Num:  (in phx) 10706624 **Filing Date:** 11/12/2003

Effective Filing: 11/12/2003

(Location History) (Foreign/Continuity Data)

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Examiner: 61092 PASCHALL, MARK (Assignment Data) **Group Art Unit:** 3742 **Class/Subclass:** 219/121.430

State or Country: JAPAN **Sheets/Drawing:** 1 **Total Claims:** 17
Independent Claims: 3

Inventors:

Last name, First name: **City:** **Country or State:**

SHIMIZU, AKIRA TOKYO JAPAN

NANBA, KUNITOSHI TOKYO JAPAN

Attorneys: ALL **Attorney Docket No:** ASMJP_104DV1

Interference No: **Lost Case No:** **Unmatched Petition No:** **L&R Code:** 1



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APPLICANTS

Akira Shimizu, Tokyo, JAPAN;

Kunitoshi Nanba, Tokyo, JAPAN;

** CONTINUING DATA *****

This application is a DIV of 10/068,092 02/05/2002 PAT 6,764,572 *OK*.** FOREIGN APPLICATIONS ***** *OK*JAPAN 2001-056685 03/01/2001 *N*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 02/20/2004

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 1	TOTAL CLAIMS 17	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after				
Verified and Acknowledged	Examiner's Signature <i>[Signature]</i>	Initials <i>[Initials]</i>		

ADDRESS

20995
 KNOBBE MARTENS OLSON & BEAR LLP
 2040 MAIN STREET
 FOURTEENTH FLOOR
 IRVINE, CA
 92614

TITLE

Method for semiconductor wafer etching

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		<input type="checkbox"/> 1.16 Fees (Filing)
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